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PATENT
Attorney Docket No.: SAM-0256
Customer No.: 29344

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Sung-Un Kwean, et al. Examiner: Umez Eronini, Lynette T.
Serial No.: 09/993,832 Group Art Unit: 1765
Filing Date: November 6, 2001
Title: ETCHING GAS COMPOSITION OF SILICON OXIDE AND METHOD OF
ETCHING SILICON OXIDE USING THE SAME

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

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TRANSMITTAL LETTER

Sir:

Enclosed herewith for filing in the above-identified patent application please find the following listed items:

1. Response to Final Office Action mailed on September 22, 2004; and
2. Return Postcard

In connection with the foregoing matter, please charge any additional fees which may be due, or credit any overpayment, to Deposit Account Number 50-1798. A duplicate copy of this letter is provided for this purpose.

Respectfully submitted,

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